

Electronic Patent Application Fee Transmittal

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| Application Number: | 10779397 | | | |
| Filing Date: | 13-Feb-2004 | | | |
| Title of Invention: | Substrate processing apparatus and substrate processing method | | | |
| First Named Inventor/Applicant Name: | Naoki Shindo | | | |
| Filer: | David Tai-Wei Yang/Deanna Fintz | | | |
| Attorney Docket Number: | 199372003910 | | | |

Filed as Large Entity

Utility under 35 USC 111(a) Filing Fees

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
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Basic Filing:

Pages:

Claims:

Miscellaneous-Filing:

Petition:

Patent-Appeals-and-Interference:

Post-Allowance-and-Post-Issuance:

Extension-of-Time:

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|-----------------------------------|------|---|-----|-----|
| Extension - 1 month with \$0 paid | 1251 | 1 | 130 | 130 |
|-----------------------------------|------|---|-----|-----|

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
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| Miscellaneous: | | | | |
| Total in USD (\$) | | | | 130 |